Author Index of Volume A35

Allen, M. G., 61
An Zhichou, 265

Baltes, H., 101
Bart, S. F., 33
Boursas, A., 113
Burns, D. W., 51

Cai Benlan, 227
Cao Ruoxin, 227
Chen Bingruo, 227
Chen Changsheng, 227
Chen Lujin, 269
Claus, R. O., 161

de Jong, P. C., 23
Deng, K., 45

Elbel, T., 101
Engelstad, R. L., 51

Fan Binglin, 283
Feng, Z., 51
French, P. J., 17

Gong Jianzhong, 239
Gong Shuping, 269
Guckel, H., 51
Gunther, M. F., 161
Gu Qingxiang, 243

Hane, K., 87
Hao Yongde, 269
He Mincai, 227
Hiranaka, Y., 1
Houdeau, D., 153
Hu, M., 197
Huang, J.-B., 69, 171
Huang Peizhong, 239
Huang, Q.-A., 247
Huang Qijun, 227
Huang, W., 203
Huang Xun, 265
Hu Zongyao, 283

IJntema, D. J., 121
Iwatsuki, T., 87

Janocha, H., 143
Jiang, H., 203
Jin Zhengsheng, 221
Johnson, R. H., 93

Kaneko, H., 17
Karbassi, S., 93
Kiesewetter, L., 153
Kim, Y. W., 61
Ko, W. H., 45

Lai Zongsheng, 213
Lang, J. H., 33
Lenggenhager, R., 101
Li, Y. X., 255
Li, Z., 189, 193, 209
Lin, C., 217
Lin Hong, 269
Lin Shichang, 283
Li Qiao, 273
Liu, L., 189, 193, 209
Liu Kun, 265
Liu Meidong, 259
Long Li, 227
Lu, J., 217
Lu, S.-J., 247
Luo, C. M., 107

Ma, Q., 197
Mao, P.-S., 69, 171
Meijer, G. C. M., 23
Muro, H., 17
Murphy, K. A., 161

Nedev, N., 113
Neuteboom, H., 23
Nojiri, H., 17

Okuma, S., 87
Omata, S., 9

Pai, S. T., 107
Poll, H.-U., 137
Polla, D. L., 77

Rao Yunhua, 259

Schiller, P., 77
Schreiter, S., 137
Shen, J., 197
Shi, H., 279
Shi Binwen, 231
Shinohara, T., 17
Smirnov, N., 113
Smits, J. G., 129
Sniegowski, J. J., 51
Song, J., 107
Speldrich, B., 93
Sridhar, U., 93
Steckenborn, A., 153
Sun, X.-Q., 189
Su Yi, 75

Tamagawa, T., 77
Tan Songsheng, 175
Tavrow, L. S., 33
Terunuma, Y., 9
Tilmans, H. A. C., 121
Tong, Q.-Y., 69, 171, 247

van Drecht, J., 23

Wang, A., 161
Wang Hongye, 265
Wang Peiying, 259
Wang Tianping, 213
Wang Weiyuan, 175
Wang Xiumei, 283
Wu, X., 197
Wu Chong-ruo, 181
Wu Guangli, 213
Wu Guoan, 259
Wu Xu, 265
Wu Zhihe, 221

Xiao Yiyong, 273
Xiong, B., 217

Yamasaki, H., 1
Yao, X., 255
Ye, C., 77
Yuan Yiquan, 231
Yu Pu, 235

Zhang, D., 209
Zhang, G. X., 107
Zhang, J.-M., 153
Zhang, R.-Q., 171
Zhang Yansheng, 283
Zhang Yougao, 243
Zhao Xin-An, 175
Zheng, X., 189, 193, 209
Zhou, H., 203
Zhou Dongxiang, 269
Zhuang, Z., 279
Zhu Jun, 221
Zhu Peixia, 235
Zook, J. D., 51

Elsevier Sequoia

Subject Index of Volume 35A

Air-gap capacitor
  static and dynamic aspects of, 121
Analysis method
  practical, for interchangeability of inductance transducers, 235
Antimony
  InSb–NiSb magnetoresistance material, 273
Arsenic
  GaAs piezoelectric modulated resistors, 247

Carbon
  static friction of diamond-like carbon film in MEMS, 45
Catheter pressure sensor
  miniature piezoresistive, 197
CMOS
  array, magnetic-field sensor, 209
  model of thermoelectric radiation sensors made by, and micromachining, 101
Current sensors
  magneto-optical, constructed with ZF glass, 107

Design considerations
  of piezoelectric-on-Si microrobot, 129
Displacement and force vectors
  sensor system for measurement of 2-D, 143

Electric motors
  operational characteristics of microfabricated, 33
Electro-beam welding
  packaging technology of ultrathin film sensors by, 283
Electroplated sacrificial layers
  single- and multi-layer surface-micromachined platforms using, 61
Electrostatic switch
  fabrication process of micro, and its application to micromechanical *V–F* converter, 189
Emitter injection modulation
  lateral magnetotransistor with enhanced, 113
Etch stop
  p–n junction, 181

Fabrication process
  of micro electrostatic switch and its application to micromechanical *V–F* converter, 189
Ferroelectric ceramics
  temperature-stable high electrostrictive strain relaxer, for servo-actuator applications, 279
Fiber-optic liquid-level sensor, 161
Finite-element simulation
  of thin-film resistance, 239
Force sensor
  mechanical analysis of novel six-degree-of-freedom wrist, 203
Force vectors
  sensor system for measurement of 2-D displacement and, 143

Gallium
  GaAs piezoelectric modulated resistors, 247
Gap-unaffected linking technique
  for grating displacement transducers, 243
Gas-lubricated microbearings
  for microactuators, 69
Gear
  initial study on fabrication of sub-millimetre polysilicon, 175
Grating displacement transducers
  gap-unaffected linking technique for, 243

Human hand
  new tactile sensor like, and its applications, 9
Hydrophone
  cylindrical, made of PVDF piezoelectric polymer and its performance, 231
Hydrothermal treatment
  lead titanate powders derived from, 255

Indium
  InSb–NiSb magnetoresistance material, 273
Inductance transducer
  practical analysis method for interchangeability of, 235
Intelligent sensing system
  multi-dimensional, using sensor array, 1

JFET 3-D magnetic-field sensor
  new integrated, in VIP technology, 213

Lead
  Pb titanate powders derived from hydrothermal treatment, 255
  preparation of $PbTiO_3$ thin films by sol–gel processing, 259
  pyroelectric $PbTiO_3$ thin films for microsensor applications, 77
Liquid-level sensor
  fiber-optic, 161

Magnetic-field sensor
  array CMOS, 209
  new integrated JFET 3-D, in VIP technology, 213
Magneto-optical current sensors
  constructed with ZF glass, 107
Magnetoresistance material
  InSb–NiSb, 273
Magnetotransistor
  lateral, with enhanced emitter injection modulation, 113
Mechanical analysis
  of novel six-degree-of-freedom wrist force sensor, 203
MEMS
  static friction of diamond-like carbon film in, 45
Microactuators
  gas-lubricated microbearings for, 69
Micromachining
  model of thermoelectric radiation sensors made by CMOS and, 101
Micromechanical structuring
  new plasma-etching technique for, of quartz, 137
Micromechanical thin films
  determination of Young's moduli of, using resonance method, 153

Micromotors
Si electrostatic and electroquasistatic, 171
Microrobot
design considerations of piezoelectric-on-Si, 129
Microsensor applications
pyroelectric $PbTiO_3$ thin films for, 77

Nickel
InSb–NiSb magnetoresistance material, 273
NTC materials
negative temperature coefficient thermally sensitive powder materials for thick-film transistor, 269

Operational characteristics
of microfabricated electric motors, 33

Packaging technology
of ultrathin film sensors by electron-beam welding, 283
Photodetector
intramodulated, 227
Photothermal effect
excitation of progressive plate wave by, 87
Piezoelectric modulated resistors
GaAs, 247
Piezoelectric-on-Si microrobot
design considerations of, 129
Plasma-etching technique
new, for micromechanical structuring of quartz, 137
Plate wave
excitation of, by photothermal effect, 87
p–n junction etch stop, 181
Polarization modulation
of twisted single-mode fibers, 221
Polyvinylidene fluoride
cylindrical hydrophone made of PVDF piezoelectric polymer and its performance, 231
Pressure sensor
miniature piezoresistive catheter, 197
SOI, 17
Pressure transducer
high-sensitivity ribbed and bossed, 93
ion-beam sputtered thin-film strain-gage, 265
PSD displacement transducers
new concepts for smart signal processors and their application to, 23

Quartz
new plasma-etching technique for micromechanical structuring of, 137

Radiation sensors
model of thermoelectric, made by CMOS and micromachining, 101
Resistors
GaAs piezoelectric modulated, 247
Resonance method
determination of Young's moduli of micromechanical thin films using, 153
Resonant microbeams
characteristics of polysilicon, 51

Sensor array
multi-dimensional intelligent sensing system using, 1
Sensor system
for measurement of 2-D displacement and force vectors, 143
Servo-actuator applications
temperature-stable high electrostrictive strain relaxer ferroelectric ceramics for, 279
Silicon
array tactile sensor with piezoresistive single-crystal Si diaphragm, 193
characteristics of polysilicon resonant microbeams, 51
design considerations of piezoelectric-on-Si microrobot, 129
electrostatic and electroquasistatic micromotors, 171
fabrication of sub-millimetre polysilicon gear, 175
structure and properties of Si–metal thermopile, 217
Single-mode fibers
polarization modulation of twisted, 221
Smart signal processors
new concepts for, and their application to PSD displacement transducers, 23
SOI pressure sensor, 17
Sol–gel processing
preparation of $PbTiO_3$ thin films by, 259
Static and dynamic aspects
of air-gap capacitor, 121
Static friction
of diamond-like carbon films in MEMS, 45
Strain resistance
finite-element simulation of thin-film, 239
Structure
and properties of Si–metal thermopile, 217
Surface-micromachined platforms
single- and multi-layer, using electroplated sacrificial layers, 61

Tactile sensor
array, with piezoresistive single-crystal Si diaphragm, 193
new, like human hand and its applications, 9
Thermistors
NTC thermally sensitive powder materials for thick-film, 269
Thermopile
structure and properties of Si–metal, 217
Titanium
Pb titanate powders derived from hydrothermal treatment, 255
preparation of $PbTiO_3$ thin films by sol–gel processing, 259
pyroelectric $PbTiO_3$ thin films for microsensor applications, 77
Transducers
gap-unaffected linking technique for grating displacement, 243
ion-beam sputtered thin-film strain-gage pressure, 265
practical analysis method for interchangeability of inductance, 235

VIP technology
new integrated JFET 3-D magnetic-field sensor in, 213
Voltage–frequency converter
fabrication process of micro electrostatic switch and its application to micromechanical, 189

Wrist force sensor
mechanical analysis of novel six-degree-of-freedom, 203

Young's moduli
determination of, of micromechanical thin films using resonance method, 153

ZF glass
magneto-optical current sensors constructed with, 107

RG